

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Gu, et al.	
Application No.: 10/773665	Art Unit: 2125
Filed: 2/6/04	
Title: Dynamically Coupled Metrology and Lithography	Examiner: Sheela Rao
Attorney Docket No.: IDT-1790	

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER NOTICE OF ALLOWANCE

(37 C.F.R. § 1.312)

Dear Sir:

Applicants request that the present amendments be entered.

Amendments to the specification begin on page 2 of this paper.

Amendments to the claims begin on page 4 of this paper.

Remarks begin on page 13 of this paper.